

Characterization Of A Novel Electro-Static Membrane Mirror Using Off-the-Shelf Pellicle Membranes

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Introduction

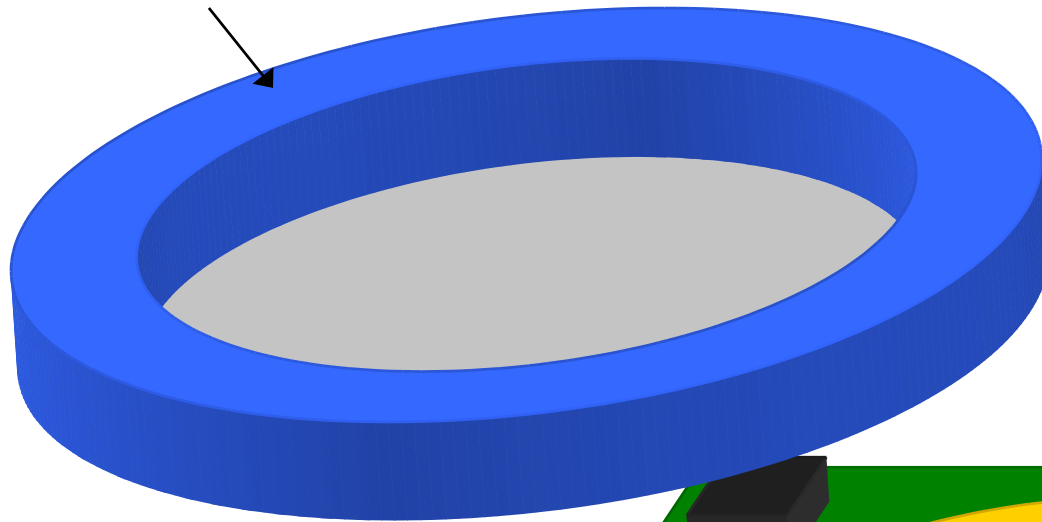


- **Membrane Mirrors**
 - Low Cost, Compact Alternative for AO
 - ~\$10/Actuator vs ~\$1000/Actuator
- **Commercial Off-the-Shelf (COTS) Pellicle Membrane**
 - Reduces Production Costs
 - No Foundry Required
 - Rapid Low Cost Prototyping of Custom Configurations
 - Different Coatings Including Multi-layer Dielectric
 - Different Membrane Materials Possible for Different Applications
- **Proof-of-Concept Lab Investigation of Device Performance**
 - Investigate Utility of Devices for AF Projects
 - Static Measurements
 - Dynamic Closed Loop Performance
- **Applications**
 - Laser Com-Beam Control-Ophthalmology-Atmospheric Imaging

Low-Cost Polymer Deformable Mirror

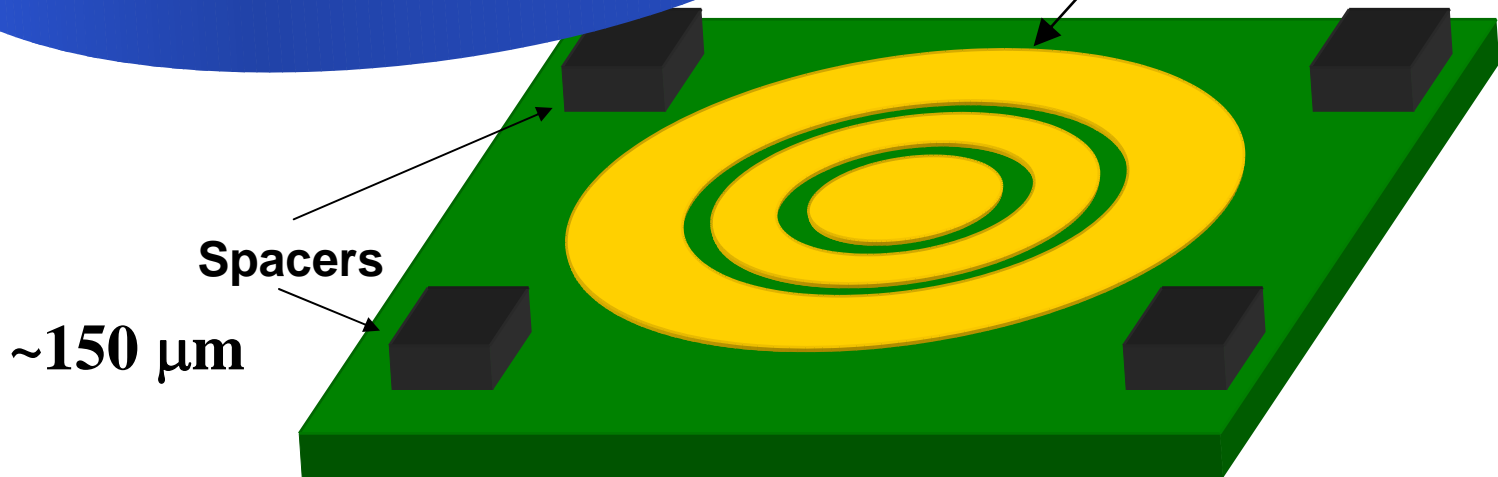


Annular Support of Membrane



Conductor-Coated
COTS Optical Membrane
Nitro-Cellulose
5 μm Thick

Electrode Array



Spacers

$\sim 150 \mu\text{m}$

PCB Board

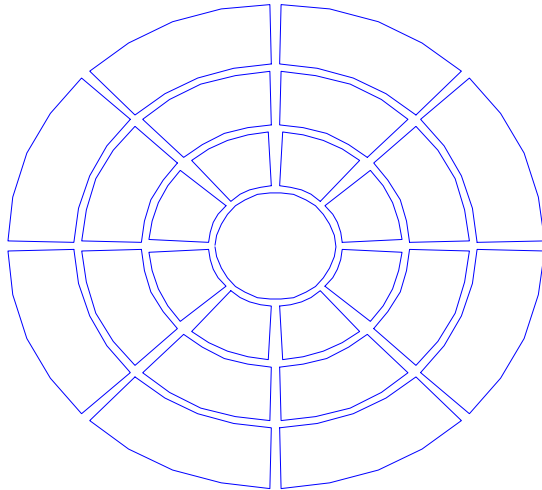
Packaged Device



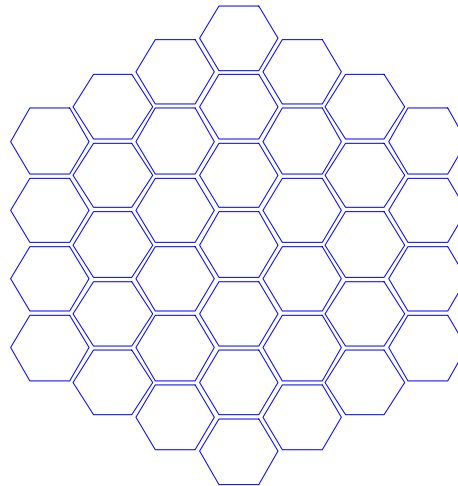
Examples of Actuator Configurations



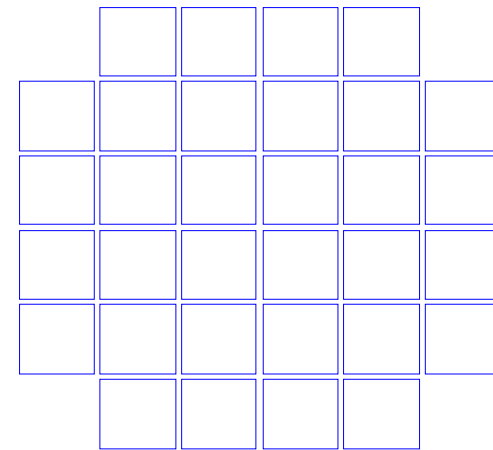
**Segmented
Annular**



Hex

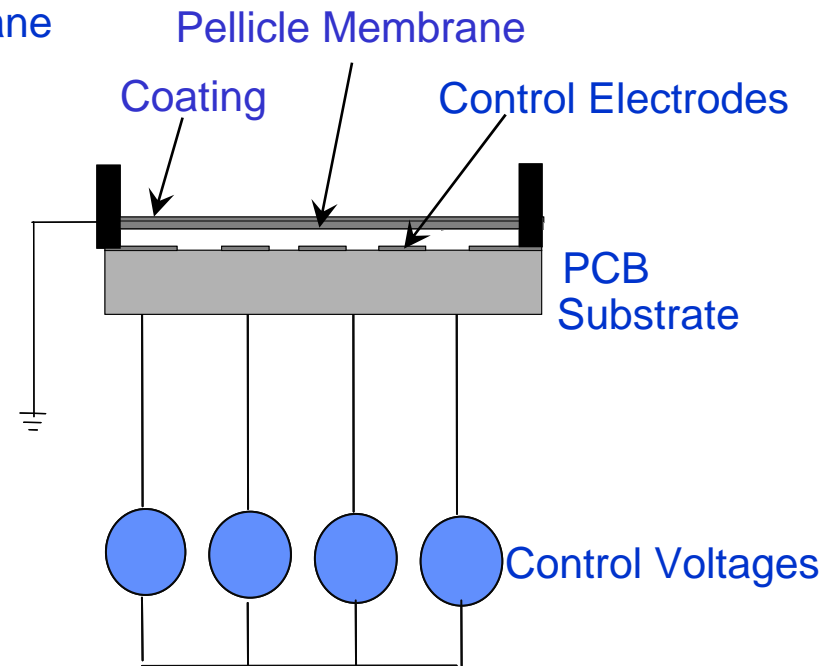
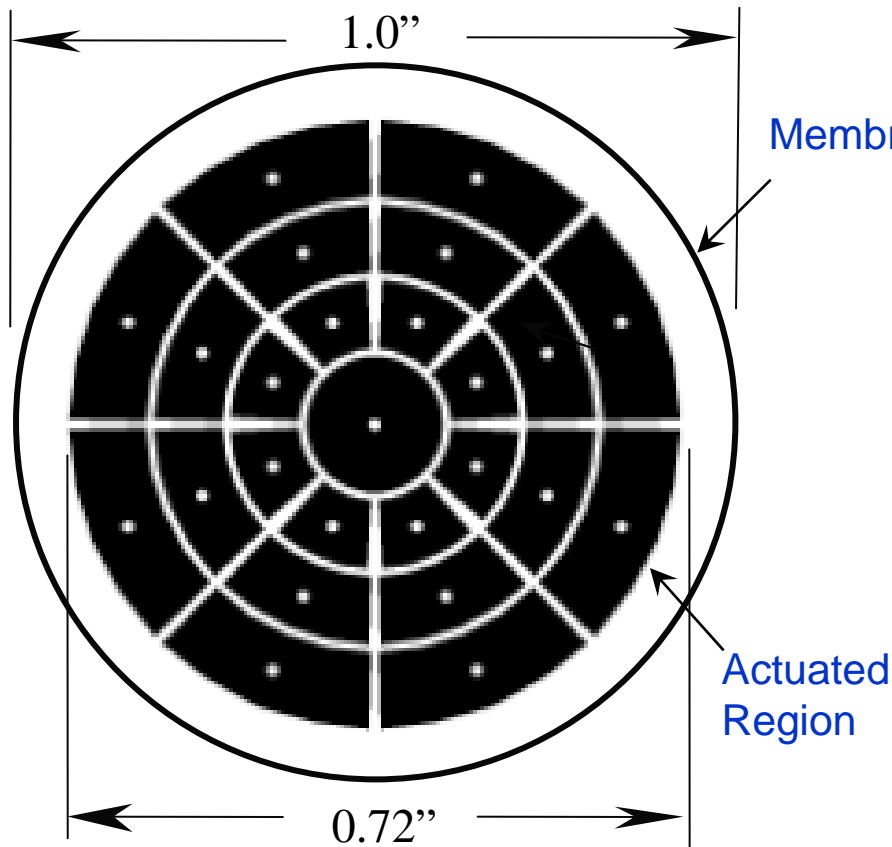


Square



**Proto-Type Device
Used in Tests
Presented Here**

AOS COTS Pellicle Membrane Mirror



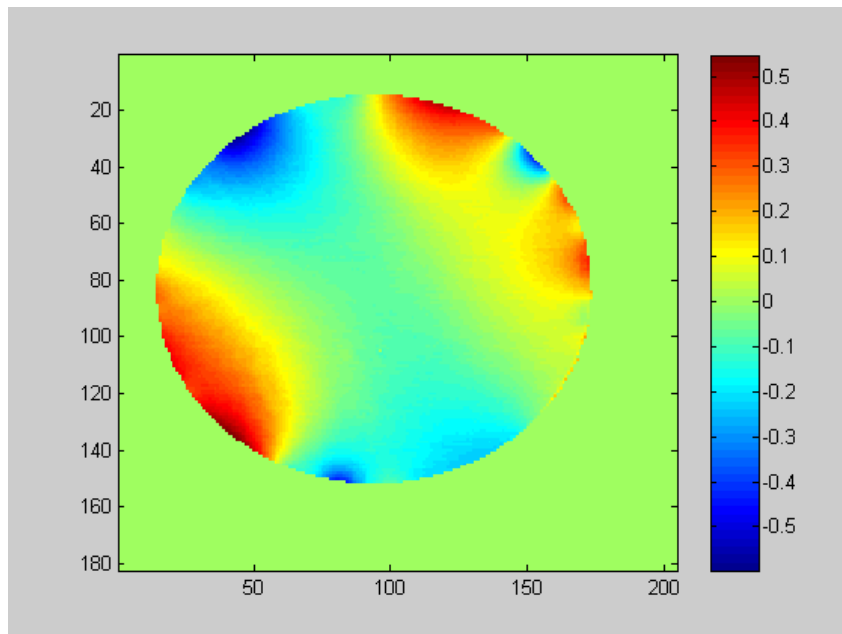
- 5 μm Polymer Membrane Stretched Over Voltage Pads
- 25 Actuators
- ~ 500 Hz First Membrane Resonance

- Actuators Can Only Pull Operate Around a Static Bias
- Designed for 300 V Max 280 V Used in Tests

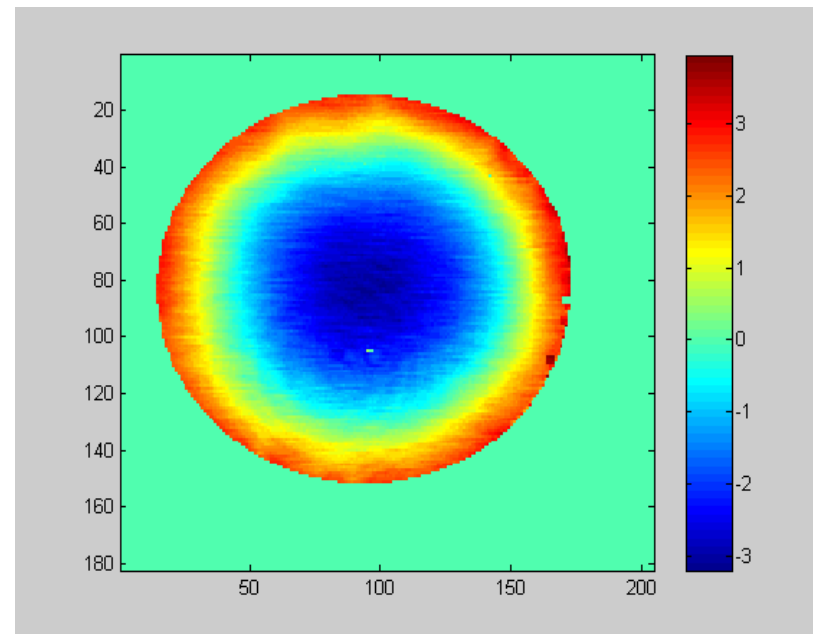
Mirror Surface Measurements (Mechanical)



Phase Shift Interferometer Measurement 632 nm



**0 Volts to All Actuators
Peak-Valley 1.14 Waves**



**280 Volts to All Actuators
Peak-Valley 7 Waves
Static Aberration Subtracted**

Influence Function Calculation



$$\nabla^2 S(\rho, \theta) = -F / T(\rho, \theta) \quad \text{Poisson Equation}$$

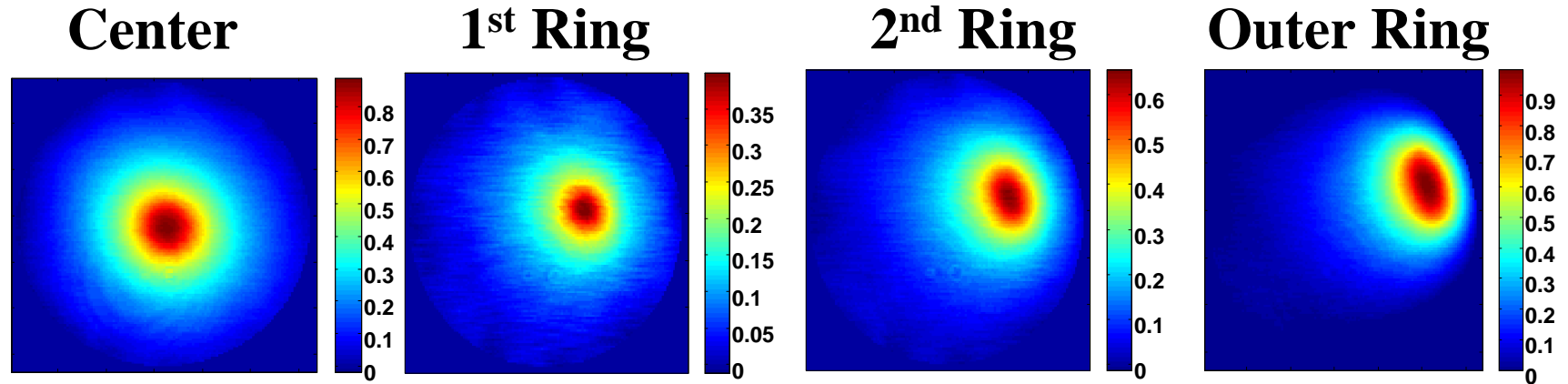
$$F = -\frac{\epsilon_0}{2} \left(\frac{V}{d} \right)^2$$

Ideal Capacitor Equation

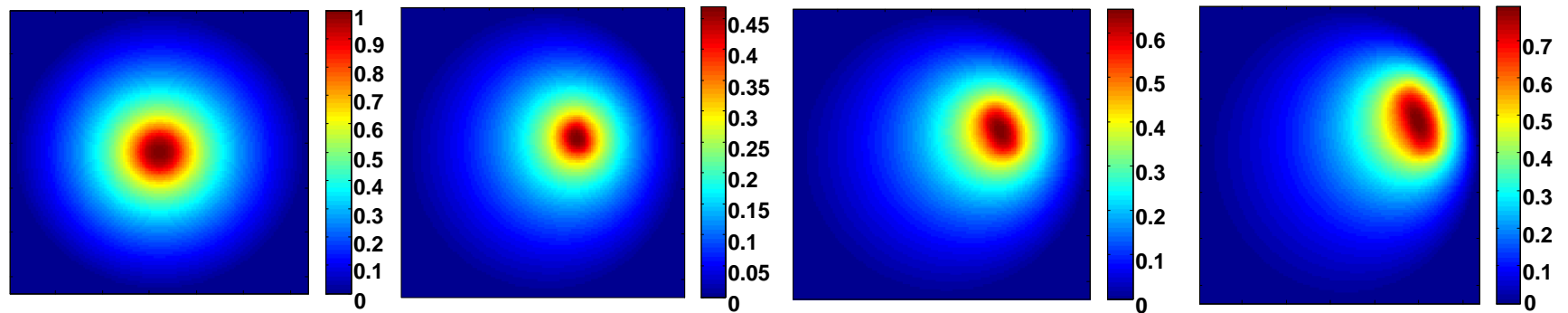
Solve Subject to Boundary Condition of Fixed Annular Support

Numerical Solution Outlined in Claflin & Bareket JOSA (1986)

Influence Functions Along One Radial



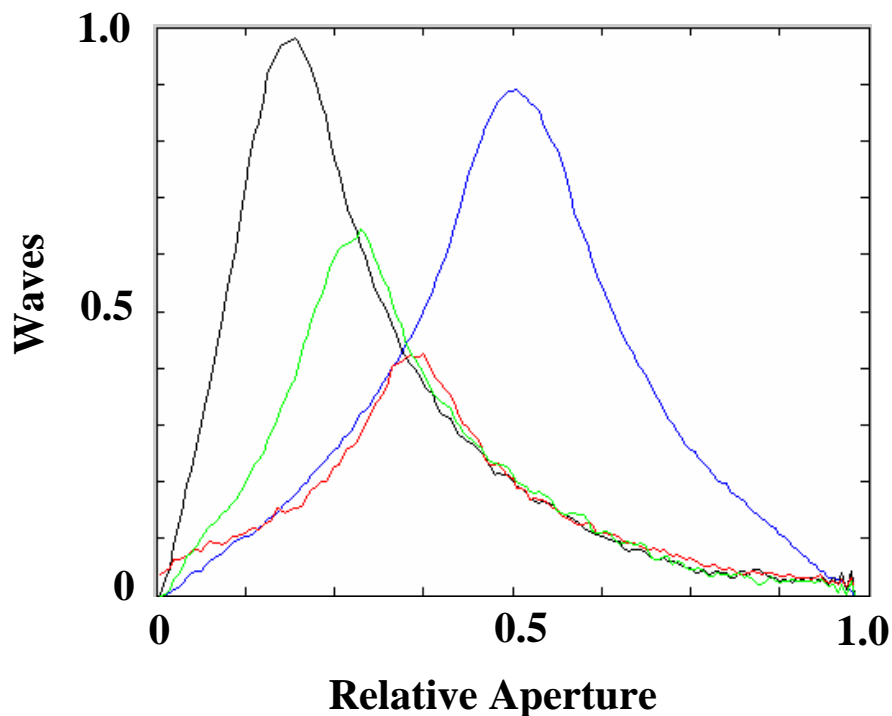
Measured -- Static Aberration Subtracted



Influence Functions

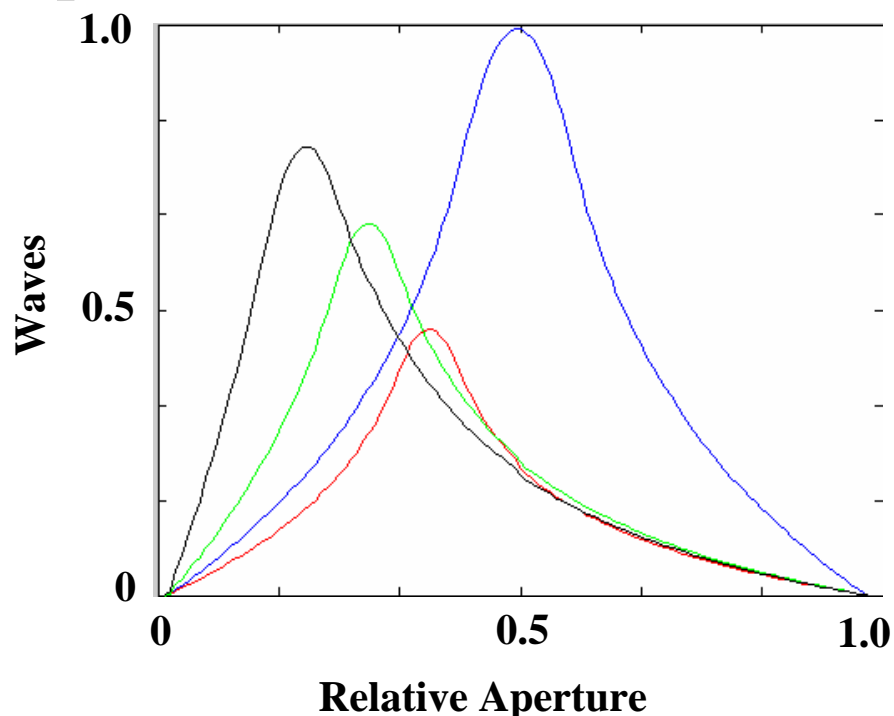


Close Comparison - Shape of Measured and Theoretical Modes Some Variations in Electrode Response



Cross-Section

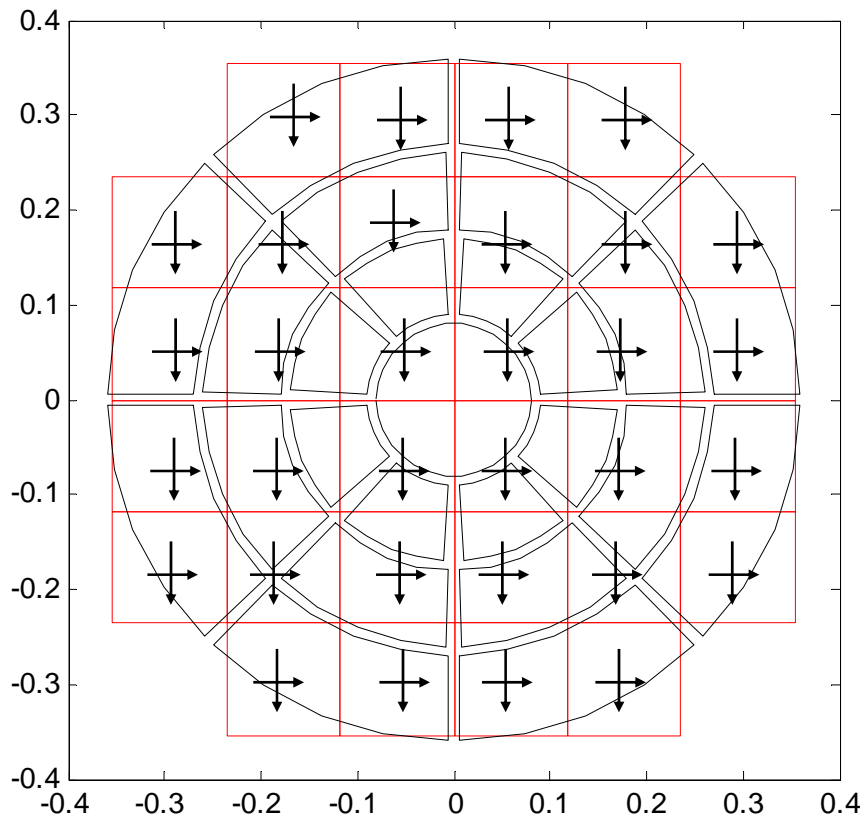
Measured Influence Functions



Cross-Section

Calculated Influence Functions

Shack-Hartmann Lensletts



-Shack-Hartmann WFS
Measures Slopes Over
Lenslet Apertures

-Fried Approximation

$$\begin{matrix} a & b \\ \square & \\ c & d \end{matrix} \quad \nabla_x = \frac{(b-a) + (d-c)}{2}$$

$$\nabla_y = \frac{(c-a) + (d-b)}{2}$$

$$\begin{bmatrix} \nabla_x \\ \nabla_y \end{bmatrix} = \Gamma_{WFS} [Wavefront]$$

$$Wavefront = \sum_{i=1}^{25} a_i Mode_i$$

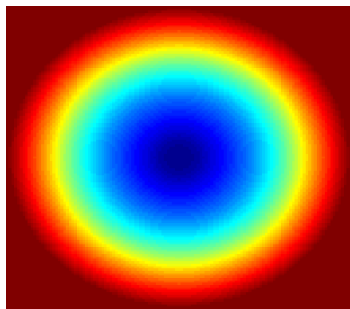
SVD Approach to Controller Derivation



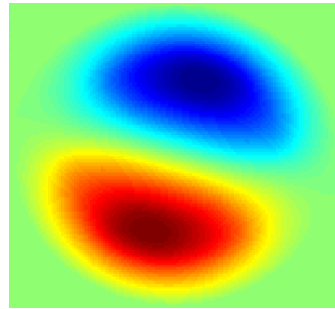
$$H = (\Gamma_{WFS} \textit{Wavefront})^{-1}$$

- **Natural Mirror Modes Not Orthogonal**
- **Singular Value Decomposition for Pseudo-Inverse**
 - Derive a Set of Orthogonal Modes Spanning Same Space
 - Expand Mirror Modes in Terms of Orthogonal Modes
 - Discard Modes with Low Singular Values to Improve Stability
 - Calculations in MATLAB

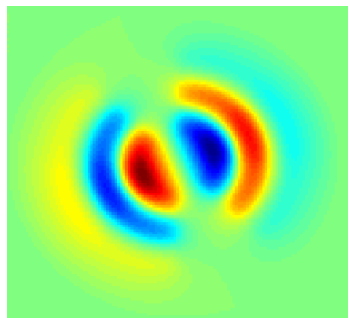
SVD Modes



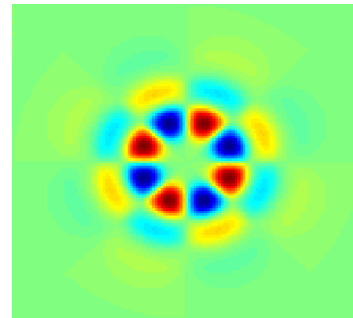
1



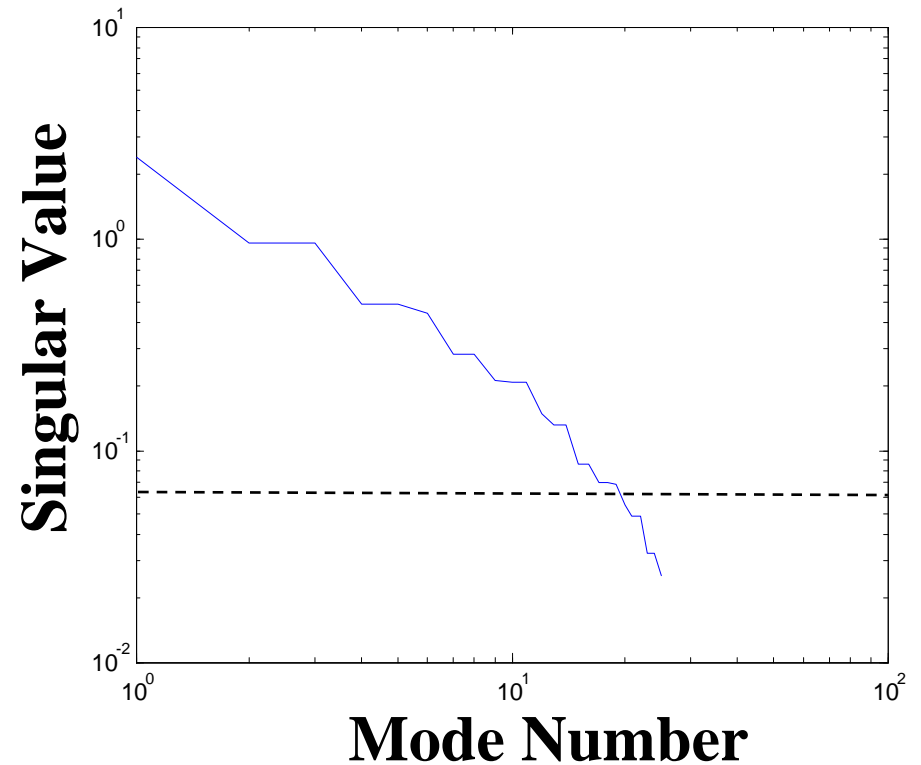
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17

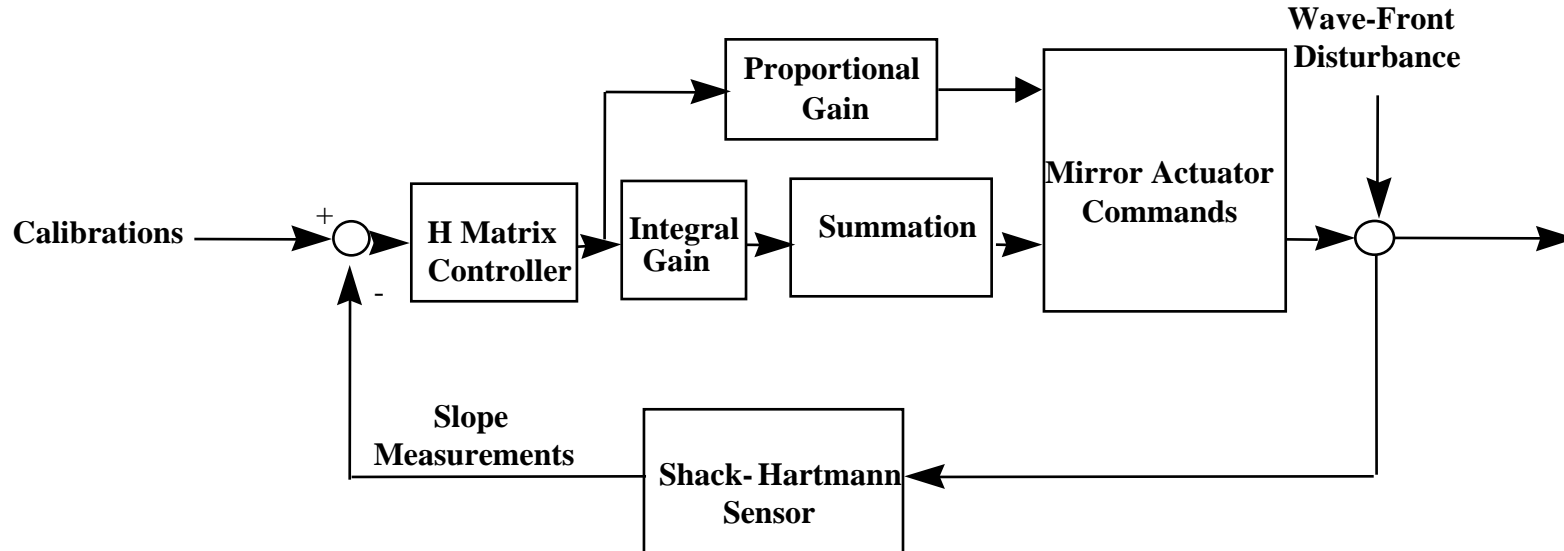


25



Stability Improved By Discarding Modes With Low S.V.
At Expense of Fewer Degrees of Freedom 20 Modes Used
Correct D/r0~5 With this Number of Modes

Control Algorithm

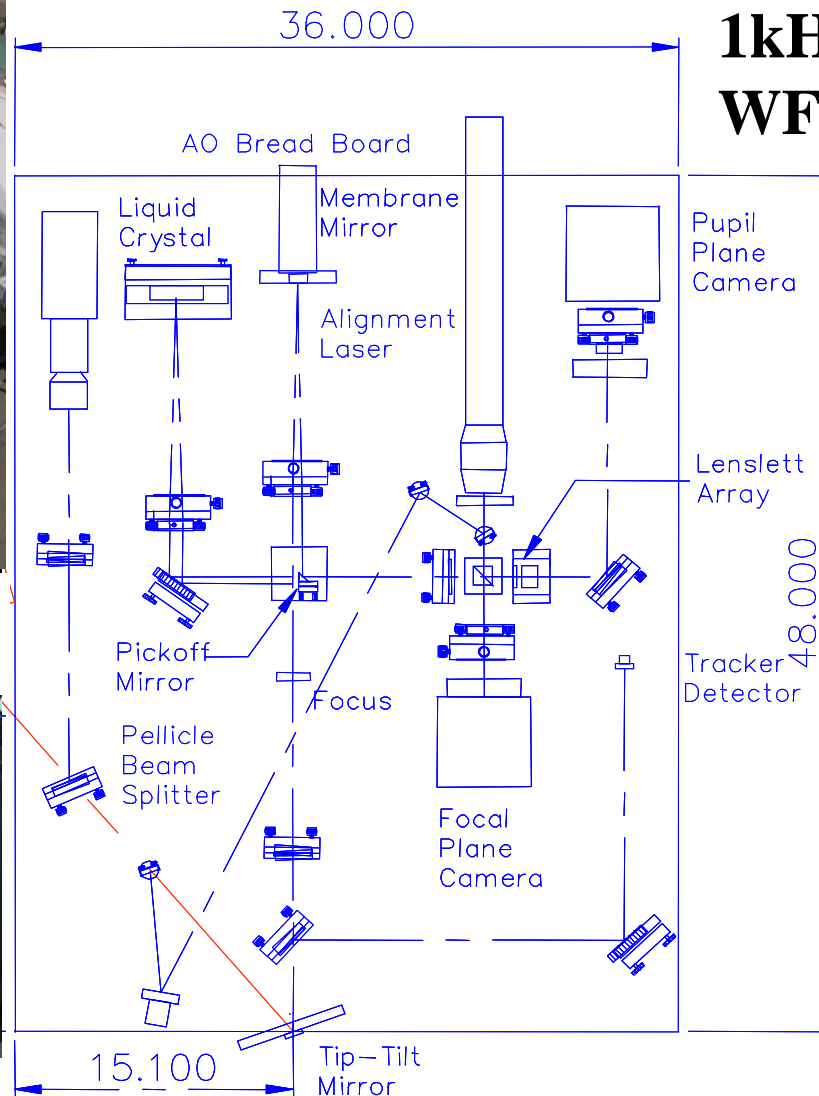


1000 Hz WFS Sample Rate
1 msec Loop Time
1 Time Step Latency

MEMS AO Test Bed



**Lexitek Spinning Phase Plate
Variable Rate Dynamic Disturbance**

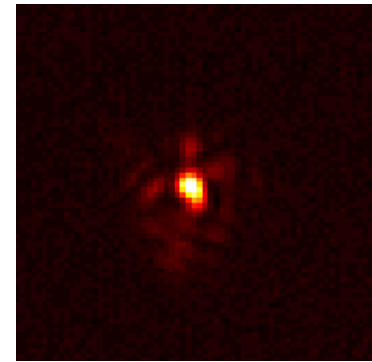
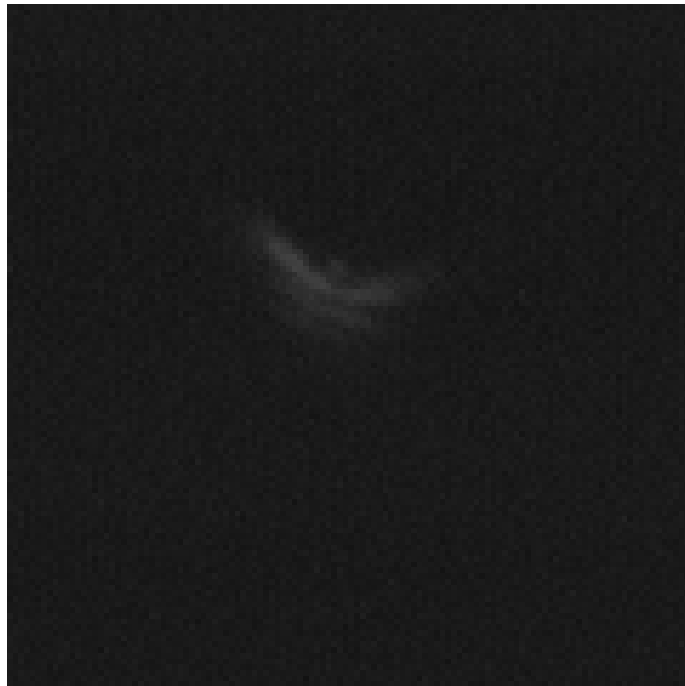


**1kHz Low Noise
WFS Camera**

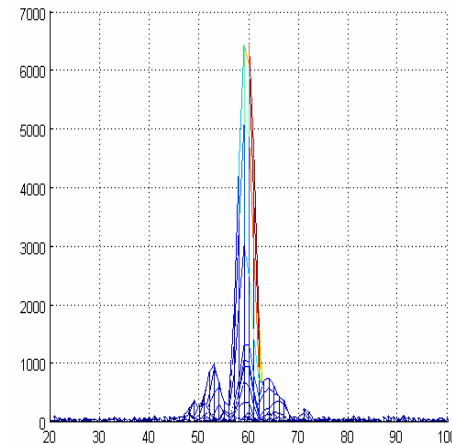
Closed Loop Experiments No Disturbance



Correct Static Aberrations



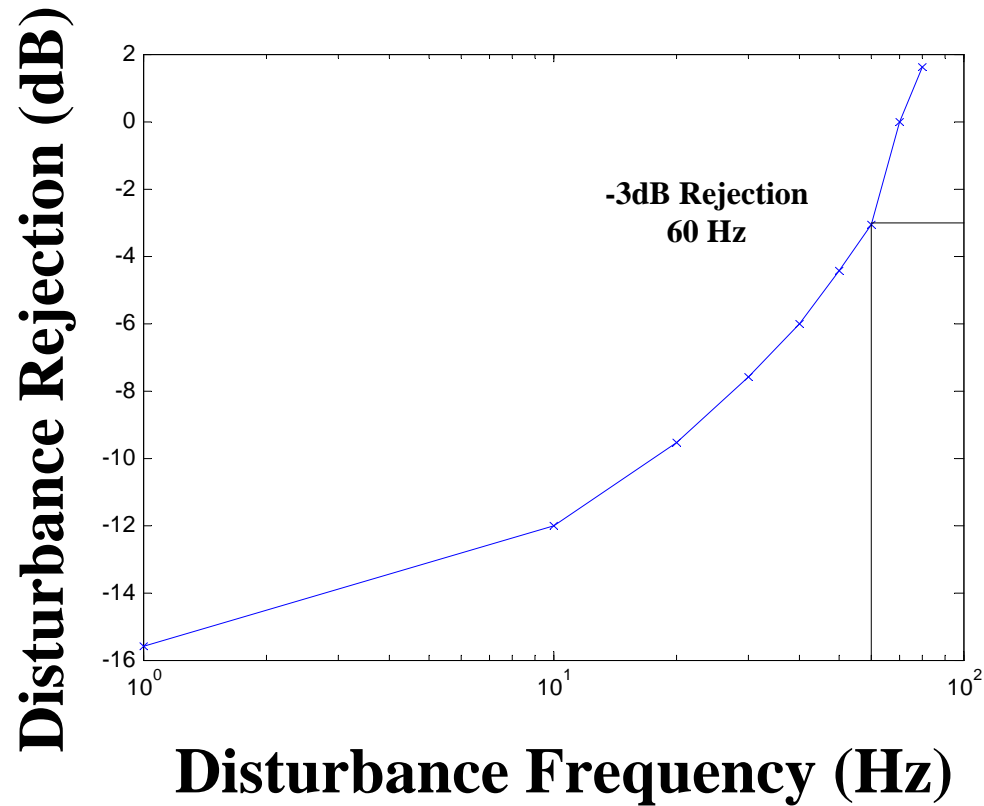
Strehl=.58



Closed Loop Temporal Bandwidth



Tilt Disturbance Rejection



Strehl Predictions

$$\text{Strehl} \cong e^{-\sigma^2} \quad \sigma^2 = \sigma_{static}^2 + \sigma_{fit}^2 + \sigma_{temp}^2 + \sigma_{snr}^2$$

$$\sigma_{fit}^2 \cong \alpha \left(\frac{r_s}{r_0} \right)^{5/3} \quad \alpha = .4 \quad \text{Membrane Mirror}$$

$$\sigma_{temp}^2 \cong \left(\frac{f_G}{f_{3dB}} \right)^{5/3} \quad \sigma_{snr}^2 \cong .35 \frac{\pi^2}{4 \text{SNR}^2}$$

Strehl Ratio Predictions

.37	.25	.16
10 Hz	40 Hz	60 Hz

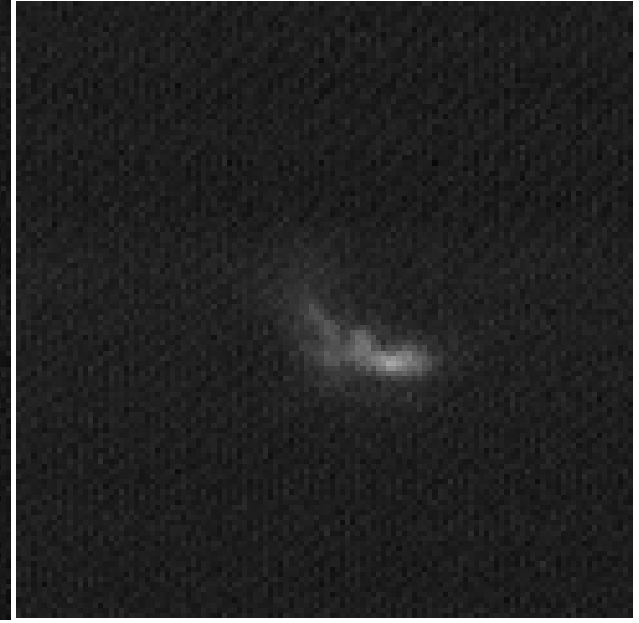
Closed Loop Experiments Dynamic Disturbance



10 Hz Greenwood Frequency



40 Hz

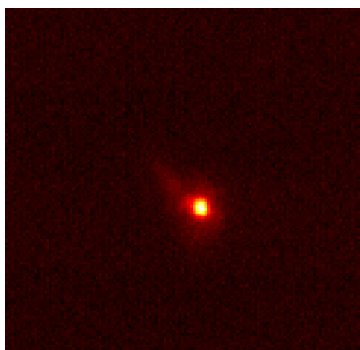


60 Hz

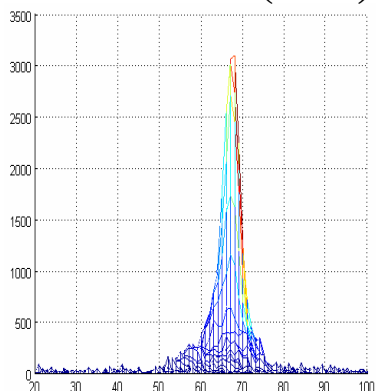
**$D/r_0=5$ Dynamic Disturbance (Spinning Phase Plate)
Different Greenwood Frequencies**

Some Residual Error Due to Uncorrected Static Aberration

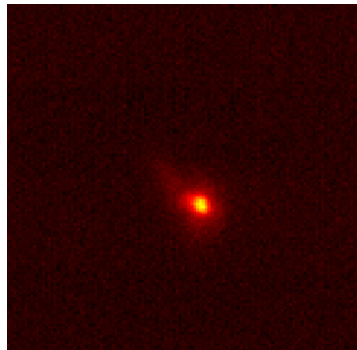
Long Exposure Closed Loop Strehl Ratio



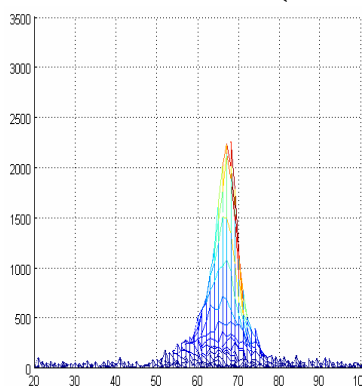
Strehl=0.28
(0.37)



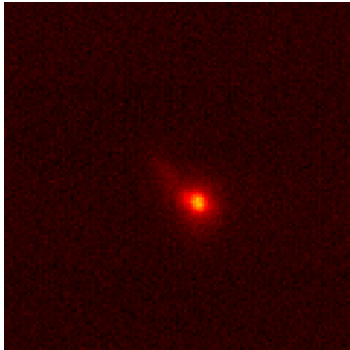
10 Hz



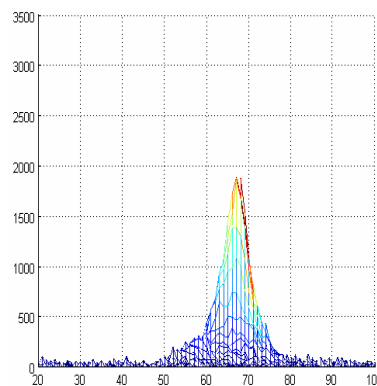
Strehl=0.20
(0.25)



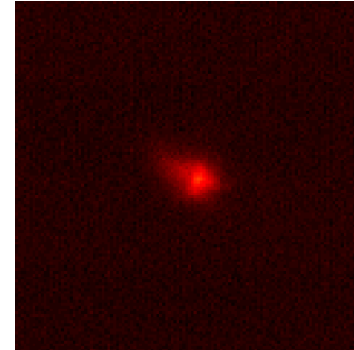
40 Hz



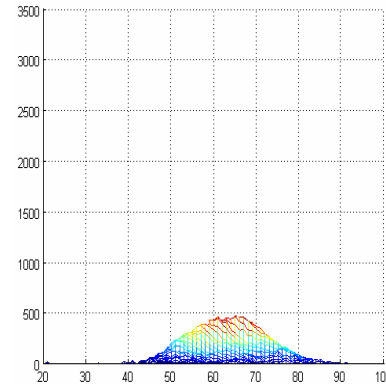
Strehl=0.15
(0.16)



60 Hz



Strehl=.05
Predicted Strehl



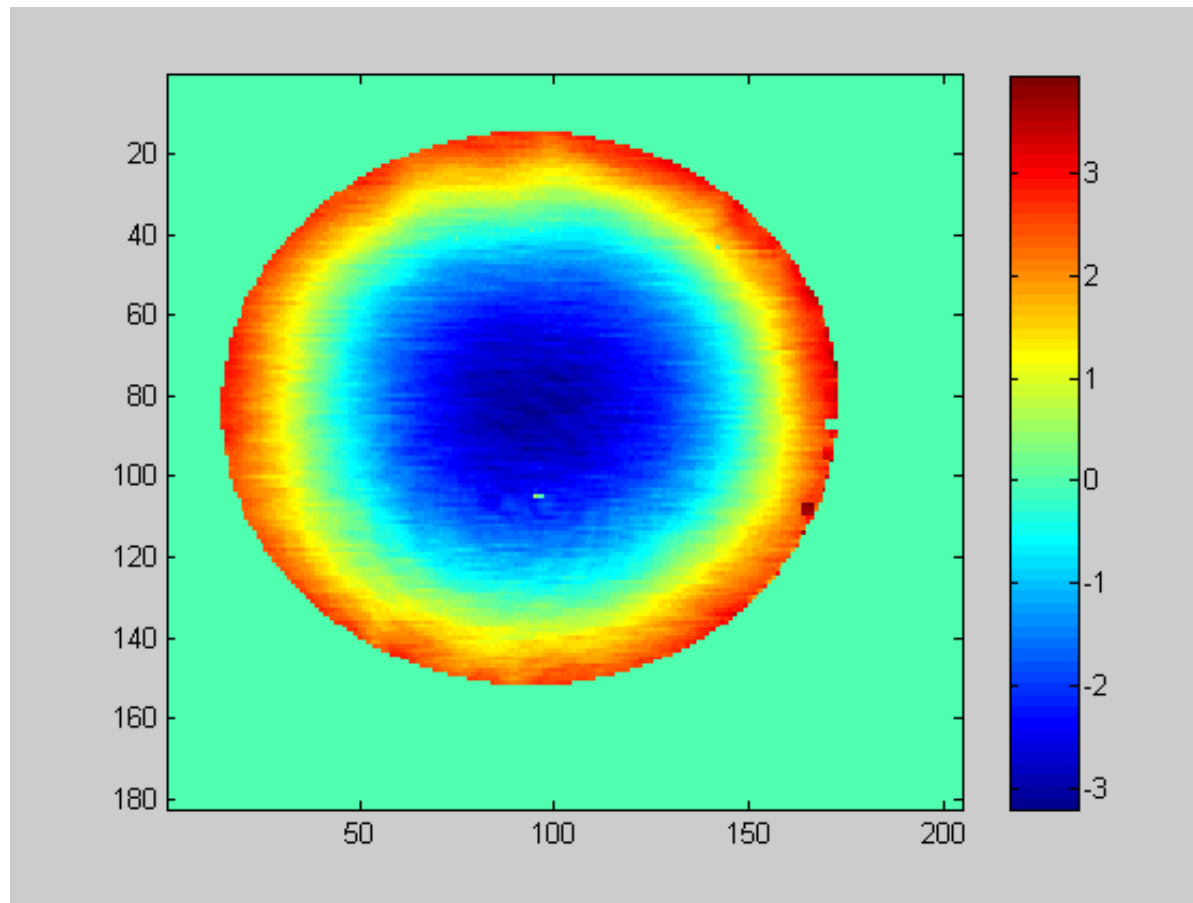
Open Loop

Conclusions



- **Membrane Mirror AO Devices**
 - Less Expensive, Low Power, Compact
- **Pellicle Membrane Mirror**
 - COTS Pellicle Nitro-Cellulose 5 μm Membrane
 - Different Membranes and Coatings for Different Applications
 - ~ 1 Wave (Mechanical) P-V Static Aberration
 - 500 Hz 1st Resonance
- **Proof of Concept Demonstration**
 - First High Speed Closed Loop Demo 60Hz - 3dB B.W.
 - Correction of $D/r_0 \sim 5$ Dynamic Disturbance with 25 Actuators
 - Static Aberrations Degrade Performance-Use up Dynamic Range
 - Increase Dynamic Range to Correct Static Aberration
 - Work With Other Actuator/WFS Configurations

Full Stroke Mirror Surface



280 Volts to All Actuators
Peak-Valley 7 Waves@ 623 nm
Static Aberration Subtracted

Pellicle Mirror Measured Influence Functions

